

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Inventor Trung Tri Doan
Assignee Micron Technology, Inc.
Priority Group Art Unit 1763
Priority Examiner Karla A. Moore
Attorney's Docket No. MI22-2471
Title Atomic Layer Deposition Apparatus and Method

PRELIMINARY AMENDMENT

To: Mail Stop Patent Application
Commissioner for Patents
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Please enter the following amendments prior to examining the above-identified application.

AMENDMENTS